

# Resource Summary Report

Generated by [NIF](#) on Sep 2, 2026

## Oxford: FlexAL ALD System Plasma Technology

RRID:SCR\_020352

Type: Tool

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### Proper Citation

Oxford: FlexAL ALD System Plasma Technology (RRID:SCR\_020352)

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### Resource Information

**URL:** <https://plasma.oxinst.com/products/ald/flexal>

**Proper Citation:** Oxford: FlexAL ALD System Plasma Technology (RRID:SCR\_020352)

**Description:** FlexAL systems provide newrange of flexibility and capability in engineering of nanoscale structures and devices by offering remote plasma atomic layer deposition processes and thermal ALD within single ALD systems.

**Resource Type:** instrument resource

**Keywords:** Oxford, Plasma Tehnology, Instrument, Resource equipment, Equipment, USEdit,

**Availability:** Commercially available

**Resource Name:** Oxford: FlexAL ALD System Plasma Technology

**Resource ID:** SCR\_020352

**Alternate IDs:** Model\_Number\_FlexAL

**Record Creation Time:** 20220129T080349+0000

**Record Last Update:** 20260829T182643+0000

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### Ratings and Alerts

No rating or validation information has been found for Oxford: FlexAL ALD System Plasma Technology.

No alerts have been found for Oxford: FlexAL ALD System Plasma Technology.

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### Data and Source Information

**Source:** [SciCrunch Registry](#)

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## Usage and Citation Metrics

We have not found any literature mentions for this resource.